

a) $E_F < E_{Fi} \Rightarrow$ substrate p-type \Rightarrow channel will be electron

nmos

b) To reach Flat band, the potential energy for holes must be lowered \Rightarrow the potential must be lowered

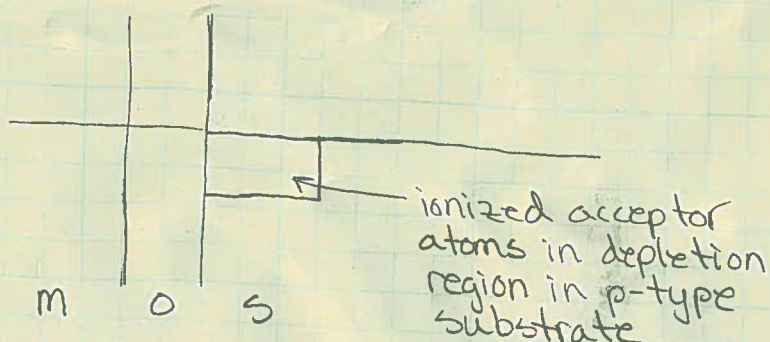
so Flat band polarity is **negative**

c) To reach threshold, E_{Fi} must drop below E_F and $\phi_s = 2\phi_{FP}$. The bands need to bend more (opposite of Flat band)

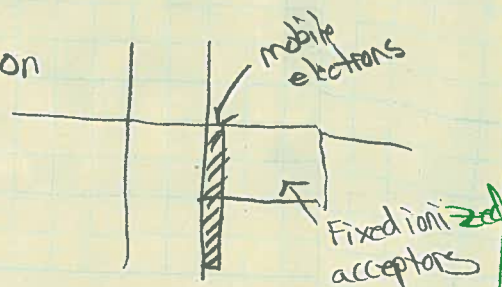
so threshold voltage polarity is **positive**

d) **Enhancement mode** since a voltage must be applied to induce the channel

e)

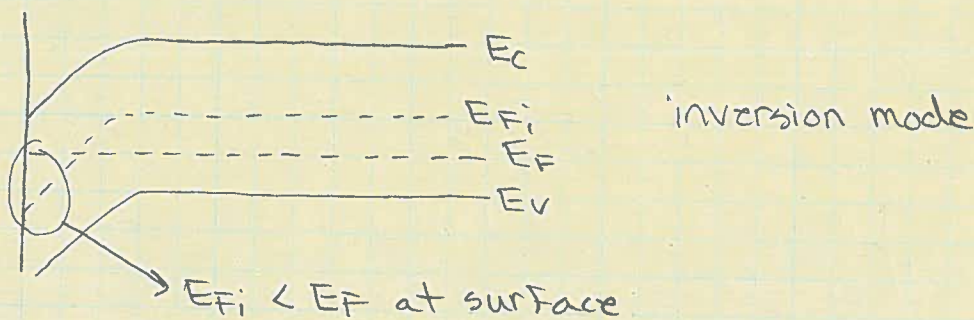


* if we bias the structure to inversion we would have

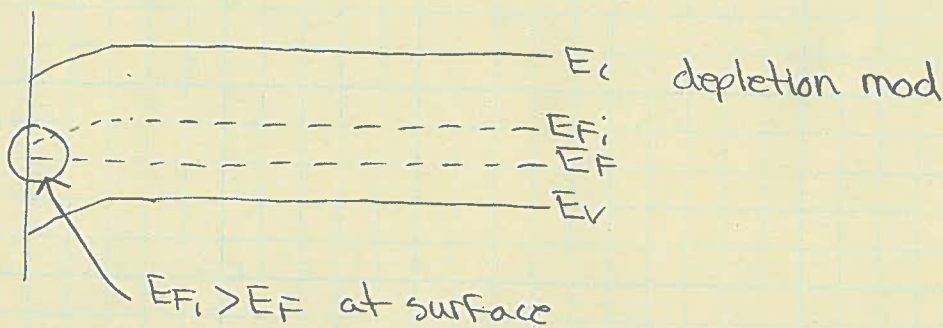


10.1

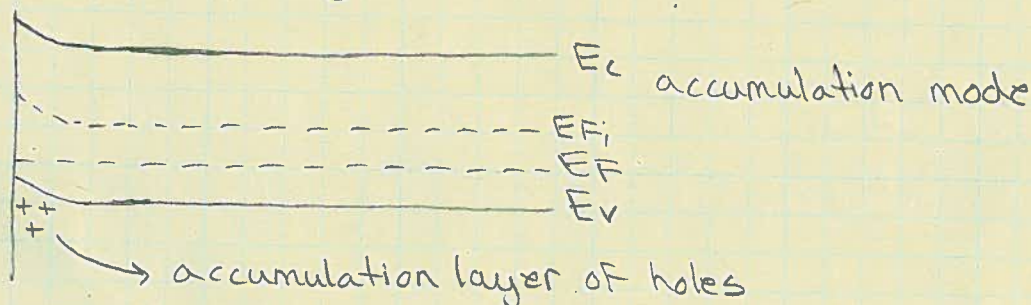
a) p-type since there is an inversion layer of electrons



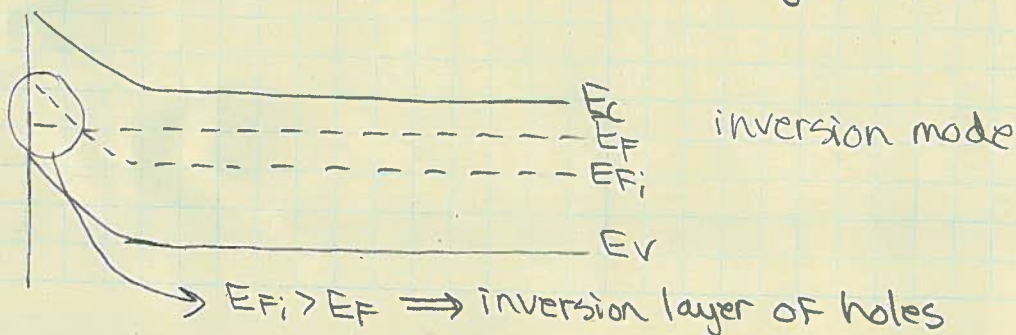
b) p-type since there are ionized negative charges (acceptors)



c) p-type since the gate charge is negative and there is an accumulation layer of holes at the surface



d) n-type since there is a depletion layer of positive charges (i.e. -donors) and a positive inversion layer (holes)



10.12

$t_{ox} = 40 \text{ nm}$ on p-type silicon with $N_a = 5 \times 10^{15} \text{ cm}^{-3}$

$$V_{FB} = -0.9 \text{ V}$$

Find ϕ_s at threshold inversion point

Find V_T , assuming no charge in oxide

Find x_{dT}

$$\begin{aligned} -\phi_s = 2\phi_{FP} &\rightarrow \phi_{FP} = V_T \ln\left(\frac{N_a}{n_i}\right) = 0.0259 \text{ V} \ln\left(\frac{5 \times 10^{15} \text{ cm}^{-3}}{1.5 \times 10^{10} \text{ cm}^{-3}}\right) \\ &= 0.3294 \text{ V} \end{aligned}$$

$$\text{so } \phi_s = 2(0.3294 \text{ V}) = \boxed{0.6588 \text{ V}}$$

$$\text{For } V_{TN} = \frac{|Q_{so}'(\text{max})|}{C_{ox}} + V_{FB} + 2\phi_{FP}$$

$$\text{need } |Q_{so}'(\text{max})| = eN_a x_{dT}$$

$$\begin{aligned} x_{dT} &= \left(\frac{4\epsilon_s \phi_{FP}}{eN_a} \right)^{1/2} = \left(\frac{4(11.7)(8.85 \times 10^{-14} \text{ F/cm})(0.3294 \text{ V})}{(1.6 \times 10^{-19} \text{ C})(5 \times 10^{15} \text{ cm}^{-3})} \right)^{1/2} \\ &= \boxed{4.13 \times 10^{-5} \text{ cm}} \end{aligned}$$

$$|Q_{so}'(\text{max})| = (1.6 \times 10^{-19} \text{ C})(5 \times 10^{15} \text{ cm}^{-3})(4.13 \times 10^{-5} \text{ cm}) = 3.304 \times 10^{-8} \text{ C/cm}^2$$

$$C_{ox} = \frac{\epsilon_{ox}}{t_{ox}} = \frac{(3.9)(8.85 \times 10^{-14} \text{ F/cm})}{(40 \times 10^{-7} \text{ cm})} = 8.629 \times 10^{-8} \text{ F/cm}^2$$

$$V_{TN} = \frac{3.304 \times 10^{-8} \text{ C/cm}^2}{8.629 \times 10^{-8} \text{ F/cm}^2} - 0.9 \text{ V} + 0.6588 \text{ V} = \boxed{0.142 \text{ V}}$$

10.16 n^+ polysilicon gate $-SiO_2$ - silicon MOS capacitor

$$t_{ox} = 18 \text{ nm}, N_a = 10^{15} \text{ cm}^{-3}, Q_{ss}' = 6 \times 10^{10} \text{ cm}^{-2}$$

\rightarrow p-substrate \rightarrow n-channel

a) Find V_{FB} ?

$$V_{FB} = \phi_{ms} - \frac{Q_{ss}'}{C_{ox}}$$

From Fig. 10.16 : $\phi_{ms} \approx -1.0 \text{ V}$

$$C_{ox} = \frac{\epsilon_{ox}}{t_{ox}} = \frac{(3.9)(8.85 \times 10^{-14} \text{ F/cm})}{18 \times 10^{-7} \text{ cm}} = 1.918 \times 10^{-7} \text{ F/cm}^2$$

$$\text{so } V_{FB} = -1.0 \text{ V} - \frac{(6 \times 10^{10} \text{ cm}^{-2})(1.6 \times 10^{-19} \text{ C})}{1.918 \times 10^{-7} \text{ F/cm}^2}$$

$$V_{FB} = -1.05 \text{ V}$$

b) Find V_T ?

$$V_{TN} = \frac{|Q_{s0}(\text{max})|}{C_{ox}} + V_{FB} + 2\phi_{FP}$$

$$|Q_{s0}(\text{max})| = e N_a x_{dT} \quad x_{dT} = \left(\frac{4 \epsilon_s \phi_{FP}}{e N_a} \right)^{1/2}$$

$$\phi_{FP} = V_t \ln \left(\frac{N_a}{n_i} \right) = 0.0259 \text{ V} \ln \left(\frac{10^{15} \text{ cm}^{-3}}{1.5 \times 10^{10} \text{ cm}^{-3}} \right) = 0.288 \text{ V}$$

$$\text{so } x_{dT} = \left(\frac{4(11.7)(8.85 \times 10^{-14} \text{ F/cm})(0.288 \text{ V})}{(1.6 \times 10^{-19} \text{ C})(10^{15} \text{ cm}^{-3})} \right)^{1/2} = 8.634 \times 10^{-5} \text{ cm}$$

$$\text{so } |Q_{s0}(\text{max})| = (1.6 \times 10^{-19} \text{ C})(10^{15} \text{ cm}^{-3})(8.634 \times 10^{-5} \text{ cm}) = 1.38 \times 10^{-8} \text{ C/cm}^2$$

$$\text{so } V_{TN} = \frac{1.38 \times 10^{-8} \text{ C/cm}^2}{1.918 \times 10^{-7} \text{ F/cm}^2} - 1.05 \text{ V} + 2(0.288 \text{ V}) = -0.402 \text{ V}$$

10.35

n-channel FET

$$k_n' = 0.6 \text{ mA/V}^2$$

$$V_T = 0.8 \text{ V}$$

$$I_D = 1 \text{ mA when } V_{GS} = 1.4 \text{ V}, V_{SB} = 0, V_{DS} = 4 \text{ V}$$

a) What is W/L ?

$$\text{For saturation } V_{DS} > V_{GS} - V_T = 1.4 \text{ V} - 0.8 \text{ V} = 0.6 \text{ V}$$

$$\text{so } V_{DS} = 4 \text{ V} > 0.6 \text{ V}$$

\Rightarrow in saturation region

$$\text{so } I_D = \frac{W \mu_n C_{ox}}{2L} (V_{GS} - V_T)^2 = \frac{k_n'}{2} \left(\frac{W}{L} \right) (V_{GS} - V_T)^2$$

$$\Rightarrow \frac{W}{L} = \frac{2I_D}{k_n' (V_{GS} - V_T)^2} = \frac{2(1 \text{ mA})}{(0.6 \text{ mA/V}^2)(1.4 \text{ V} - 0.8 \text{ V})^2}$$

$$\boxed{W/L = 9.26}$$

b) I_D ? when $V_{GS} = 1.85 \text{ V}$, $V_{SB} = 0$, $V_{DS} = 6 \text{ V}$

$$V_{GS} - V_T = 1.85 \text{ V} - 0.8 \text{ V} = 1.05 \text{ V} < V_{DS}$$

\Rightarrow saturation region

$$I_D = \frac{k_n'}{2} \left(\frac{W}{L} \right) (V_{GS} - V_T)^2 = \frac{0.6 \text{ mA/V}^2}{2} (9.26) (1.05 \text{ V})^2$$

$$\boxed{I_D = 3.06 \text{ mA}}$$

c) I_D ? when $V_{GS} = 1.2 \text{ V}$, $V_{SB} = 0$, and $V_{DS} = 0.15 \text{ V}$

since $V_{GS} - V_T = 0.4 \text{ V} > V_{DS} \Rightarrow$ linear region

$$I_D = \frac{k_n'}{2} \left(\frac{W}{L} \right) [2(V_{GS} - V_T)V_{DS} - V_{DS}^2]$$

$$= \frac{0.6 \text{ mA/V}^2}{2} (9.26) [2(0.4 \text{ V})(0.15 \text{ V}) - (0.15 \text{ V})^2] = 0.271 \text{ mA}$$